

Automated optical inspection

Image analysis and defect recognition

Marc Wenskat

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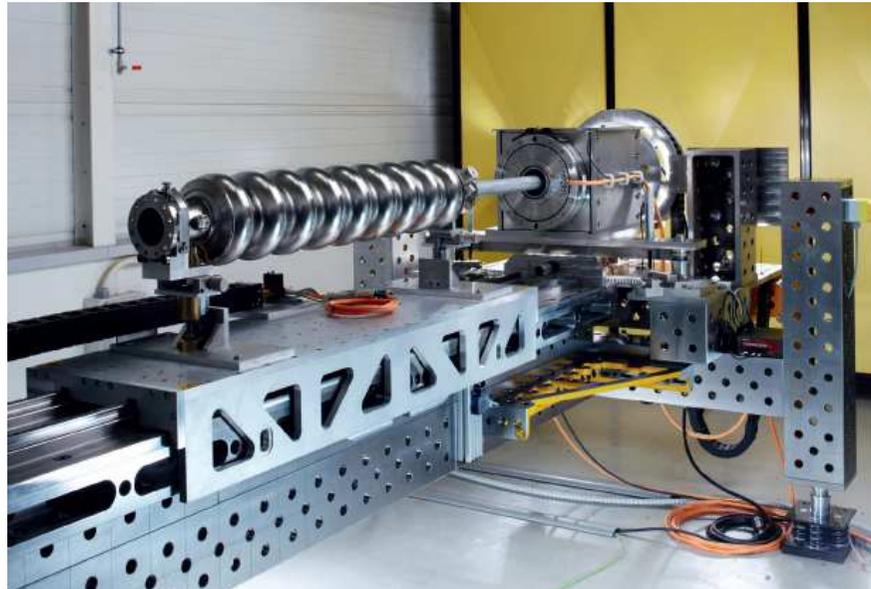
Motivation

- > Optical Inspection is a well established tool
 - Quality assurance: Check after delivery
 - Defect identification and further understanding of cavity behavior
 - Helps to understand surface treatment
- > Inspection procedure takes about several days
- > Images are analyzed by operator
- > For XFEL or ILC, this is not feasible
- > Therefore an automated setup for image taking and image analysis



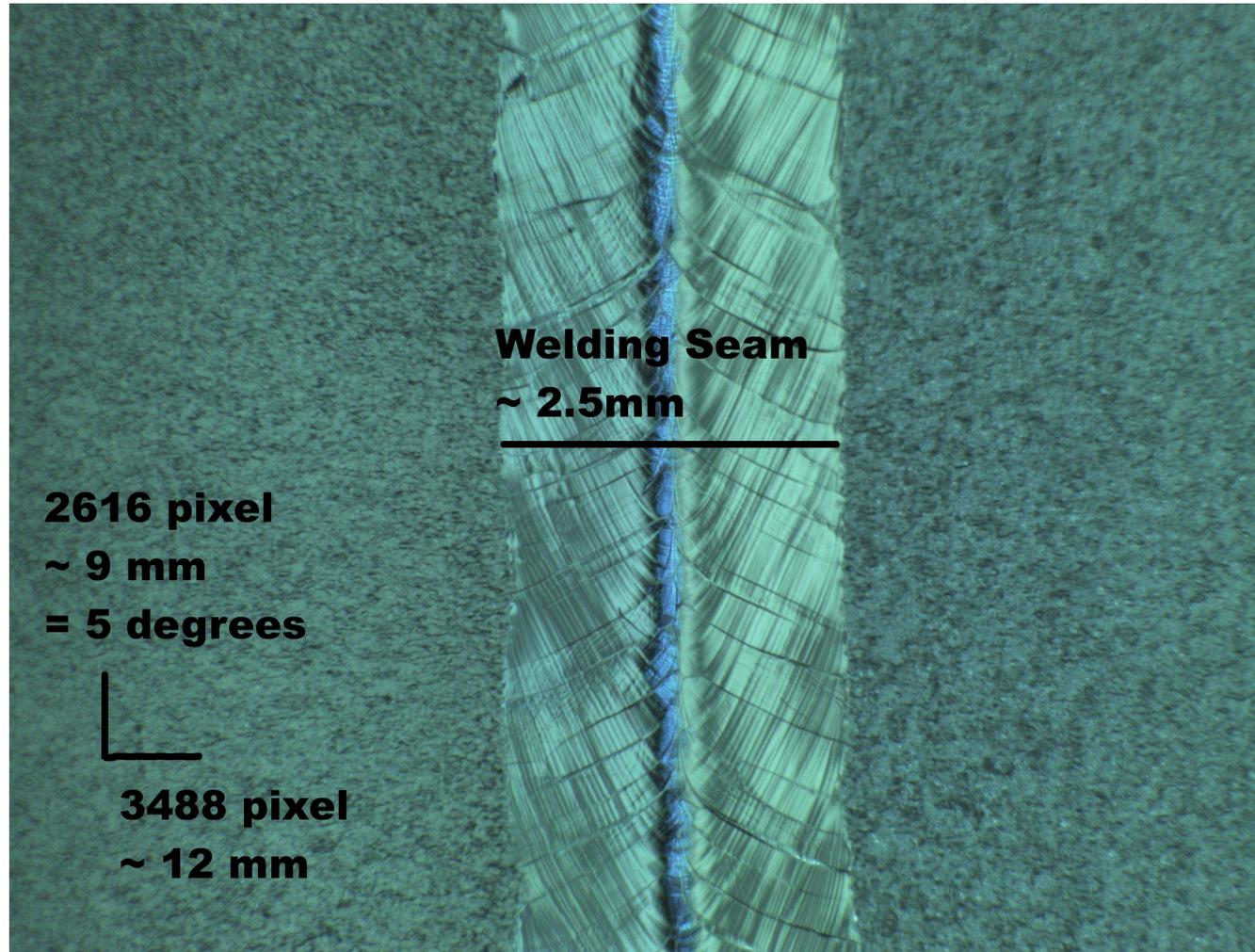
OBACHT

- > Optical bench for automated cavity inspection with high resolution and short timescales



- > Fully automated optical inspection: camera position, illumination, auto focus, image taking and image storing
- > The timescale for a single inspection decreases from the order of days to half a day
- > Image processing will run in parallel using the stored images
- > Camera system based on Kyoto Camera

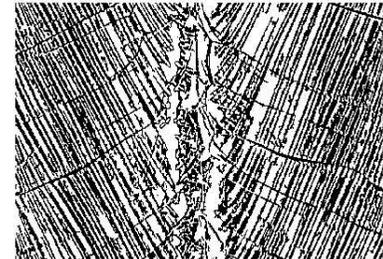
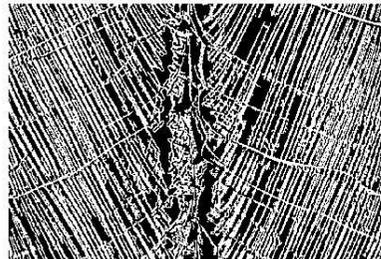
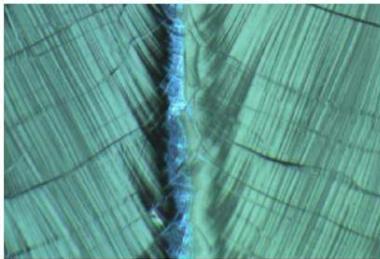
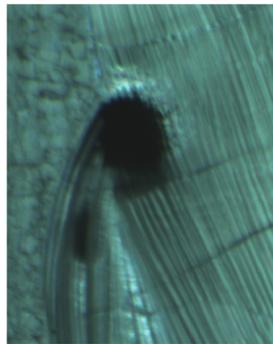
Example



- Effective resolution of $3.5 \mu\text{m} \times 3.5 \mu\text{m}$ per pixel

Image processing

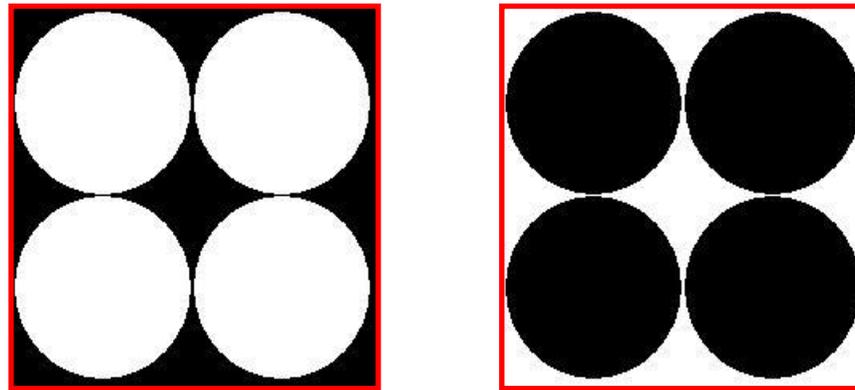
- Image processing steps are applied to the original color image
- A binary image is derived



- Sets of parameters are deduced using the image representations

Complementary representations

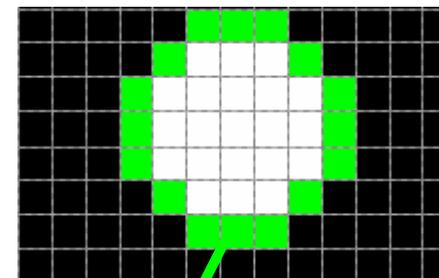
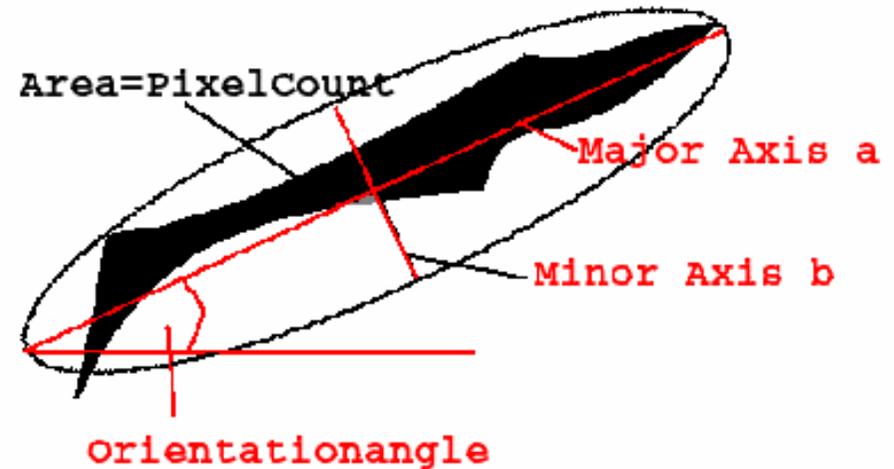
- > Define the regions with pixels equal to one as objects, regions with pixels equal to zero as background
- > In the image on the left, the algorithm derives quantities for four circular objects while for the image on the right the algorithm does this for a single object



- > Both representations are useful since they carry different information although they are just complements

Measured quantities

- > Several quantities are derived for each representation
- > Some are derived from the binary image
 - Area
 - Major & minor axis length
 - Perimeter
 - Orientation
 - Numerical eccentricity
- > Some are derived from the original image
 - Surface Roughness

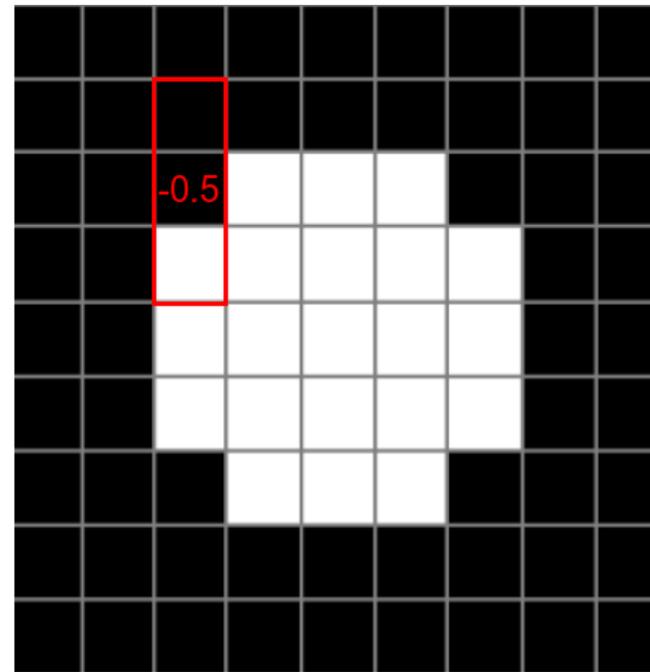
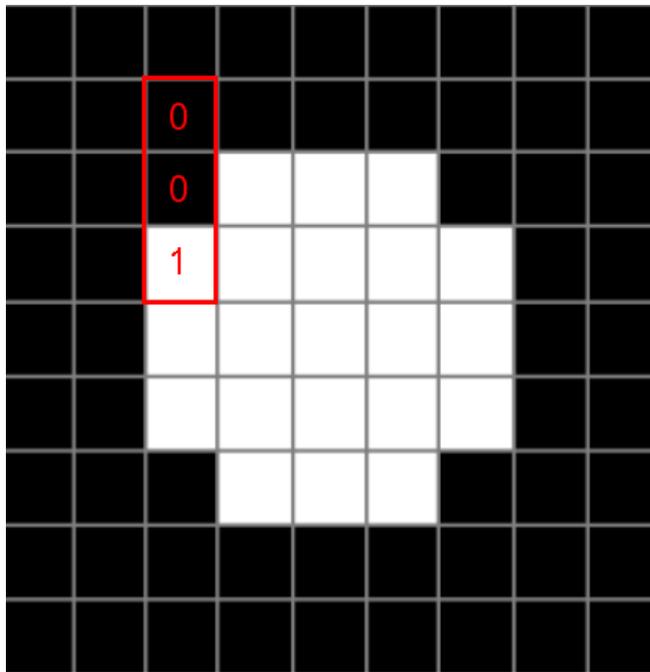


Perimeter

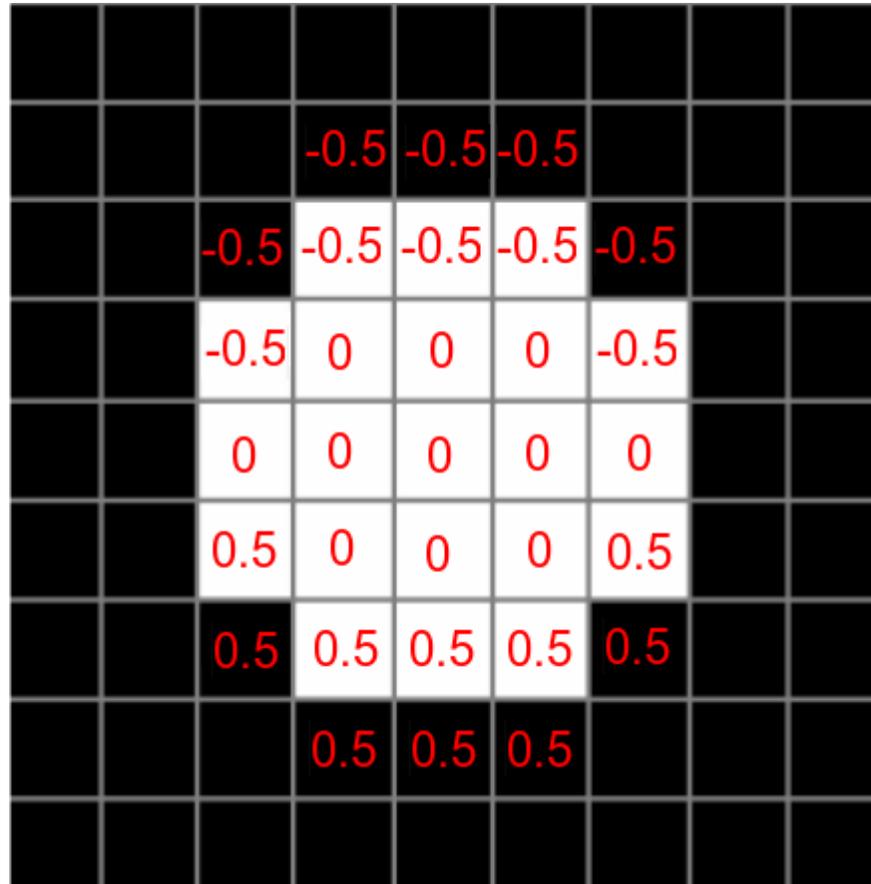
Surface Roughness

- > Pixel to pixel intensity difference is calculated (intensity gradient) for the x and for the y direction using the finite central difference

$$\frac{\Delta I(x, y)}{\Delta x} = \frac{I(x+1, y) - I(x-1, y)}{(x+1) - (x-1)} = \frac{0 - 1}{2} = -0.5$$

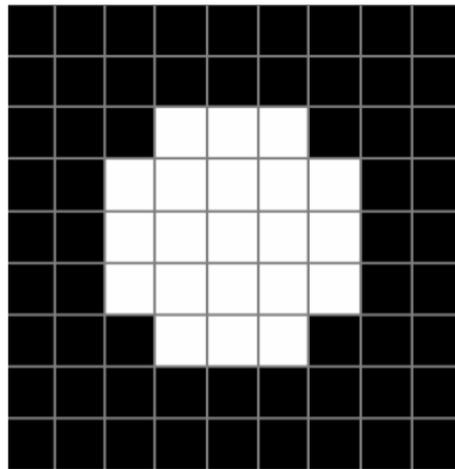


Surface Roughness

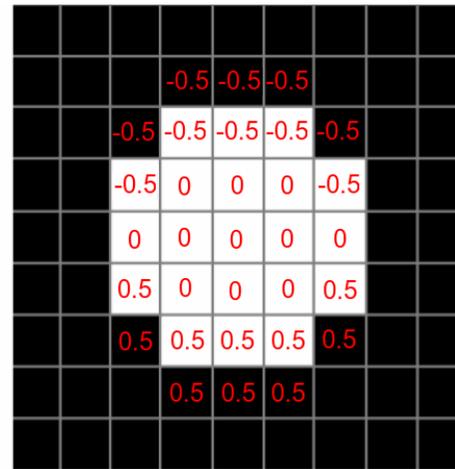


Surface Roughness

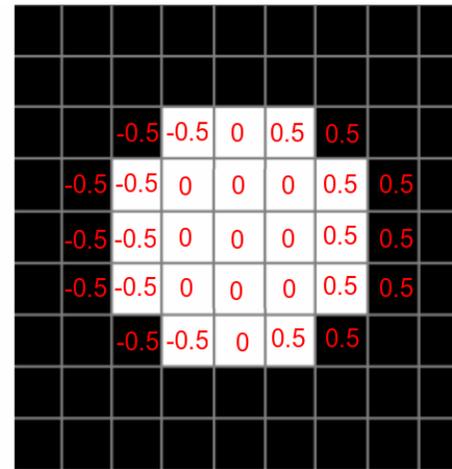
- > After doing this for the x (1) and y (2) direction, one will get two difference values for each pixel



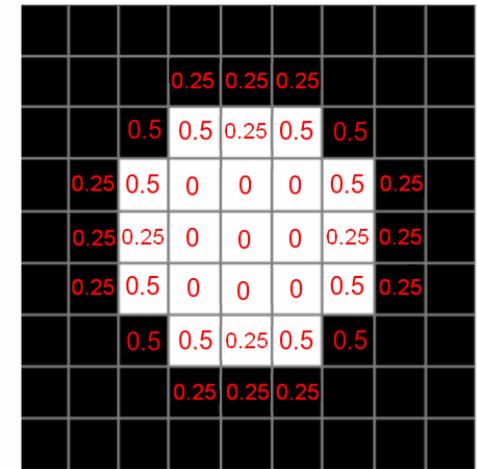
(1)



(2)



(3)



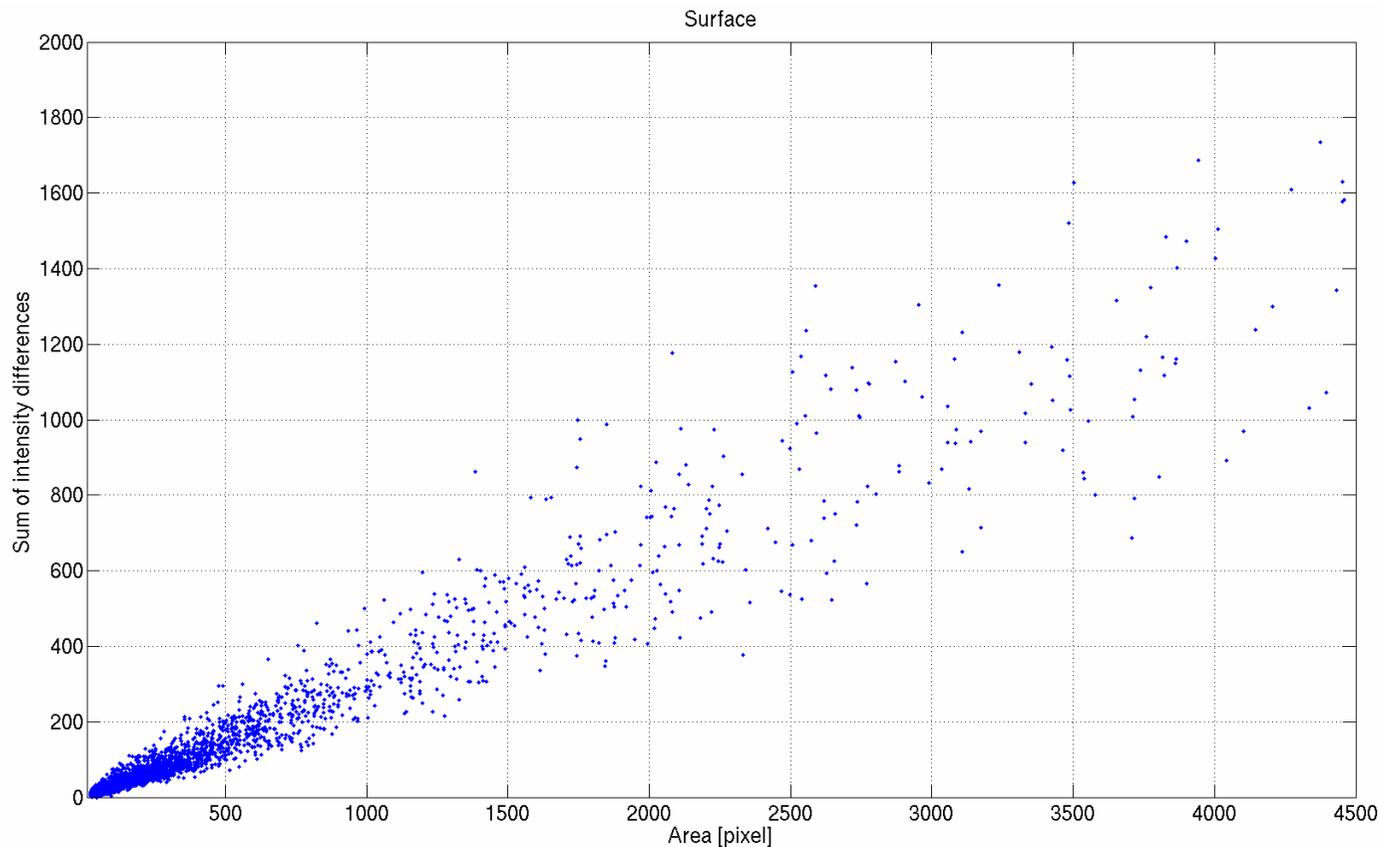
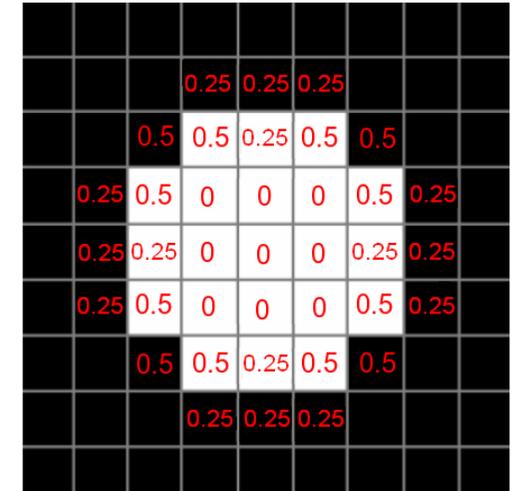
(4)

- > These two values for each pixels are squared and summed up and a single scalar value Δ for each pixel is derived (4)



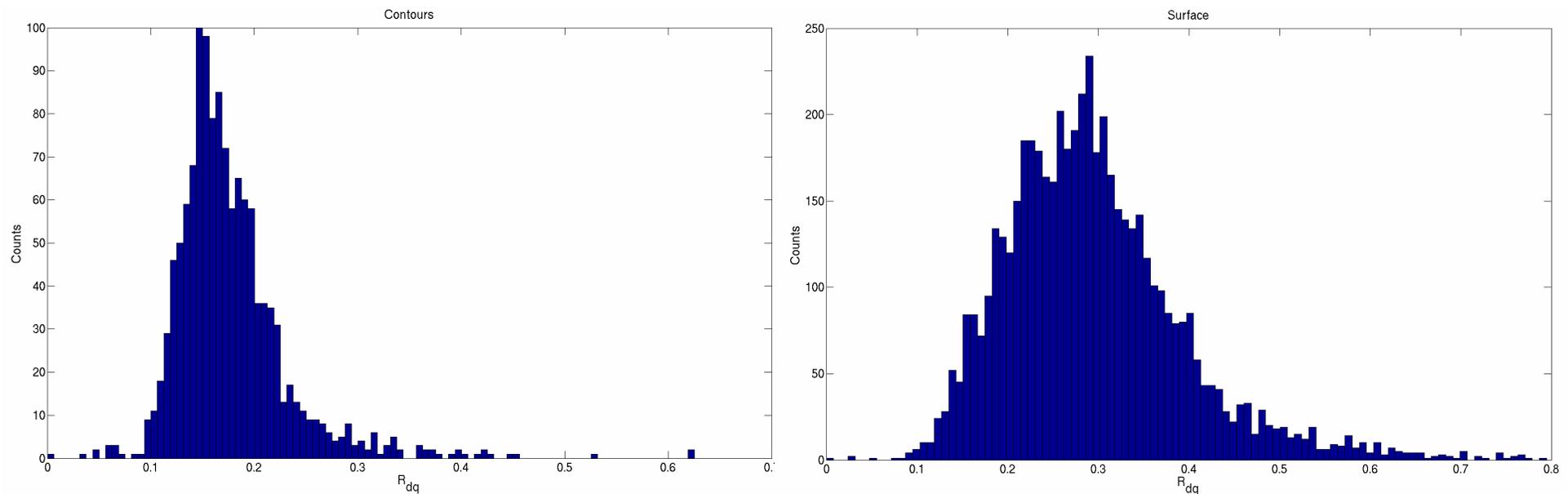
Surface Roughness

- > For an object in the image, the sum of Δ is calculated
- > In this case, the sum would be 5



Surface Roughness

- Dividing the sum by the perimeter (or the area) a measure of the slope of an edge (or a surface) is derived



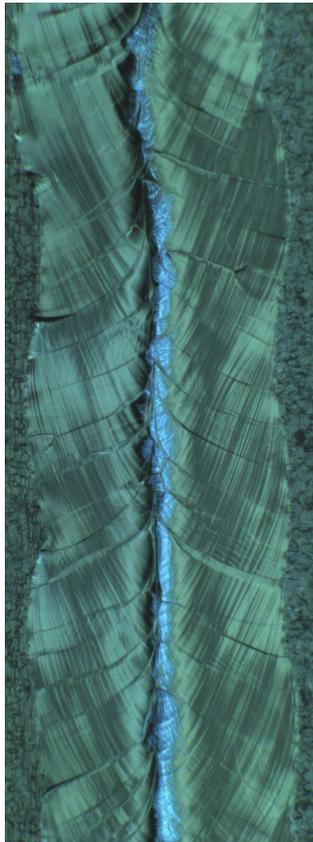
- The shape and the most likely value of the distribution can be used to characterize the surface roughness



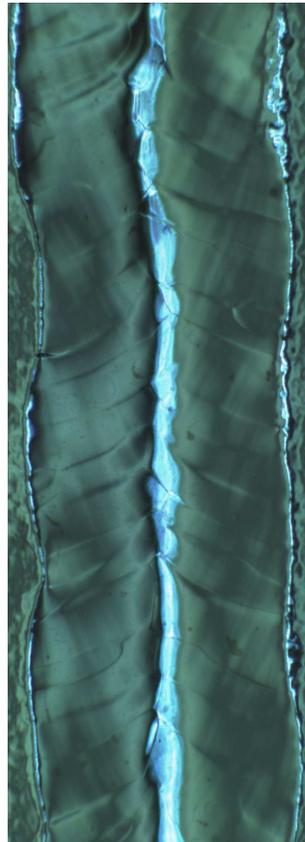
Influence of EP onto the welding seam

> Z161 – Equator 1. Example images: 0° till 4°

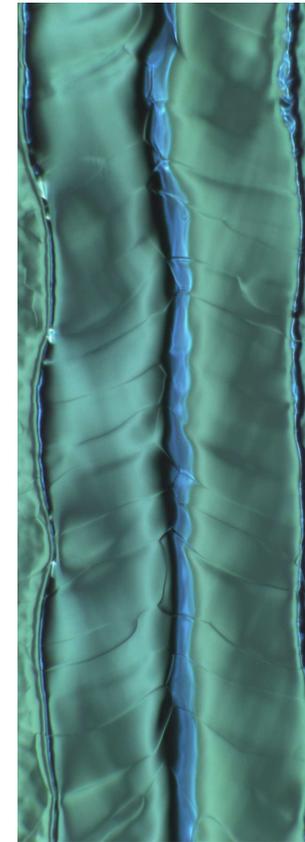
Before EP



After 1st EP



After 2nd EP



Most
likely values

$$R_{dq} = 0.312$$

$$\sigma = 0.242$$

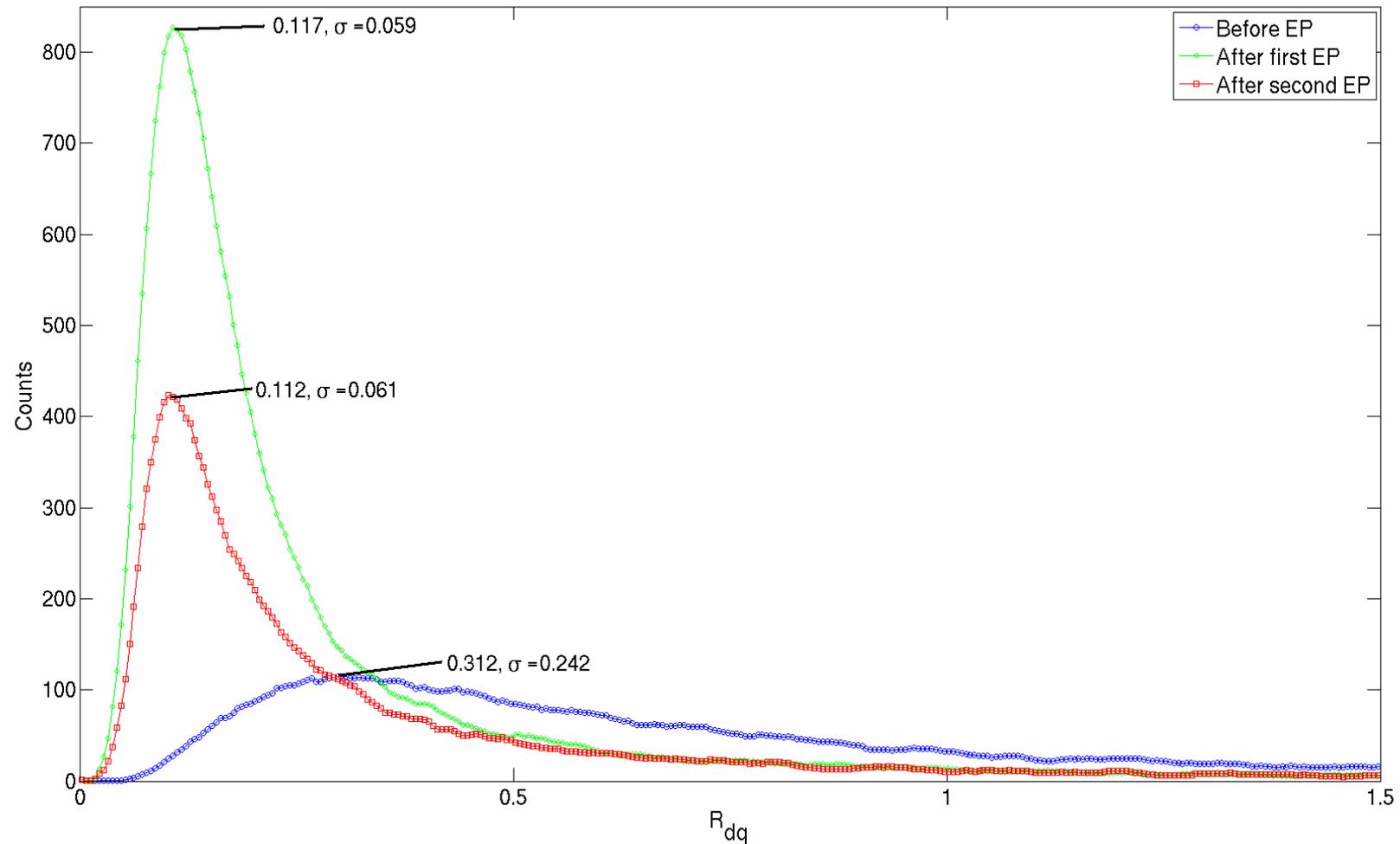
$$R_{dq} = 0.112$$

$$\sigma = 0.061$$

$$R_{dq} = 0.117$$

$$\sigma = 0.059$$

Influence of EP onto the welding seam



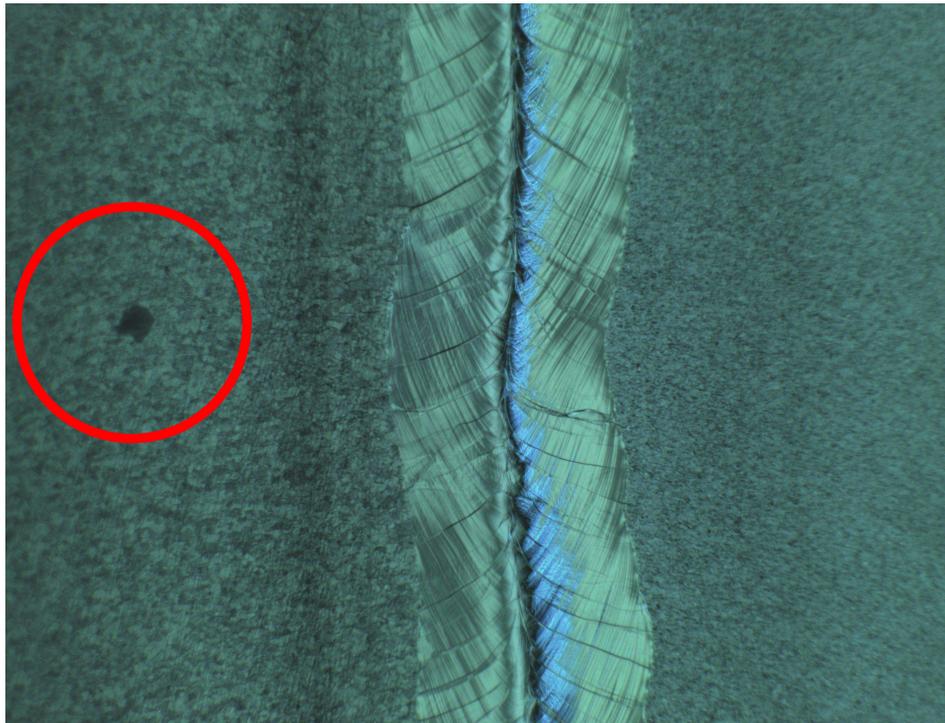
- > Most likely value decrease, > The coverage ratio before EP and after the EP changes drastically, which means the edge roughness decreases

- Before EP: 2745 objects – 12.89 mm² (51.56%)
- After EP: 2 objects – 21.92 mm² (87.68%)



Defect Recognition

- > Sets of quantities used to compare an object with the neighborhood
 - Major Axis Length, Eccentricity, Area
- > The neighborhood are all objects inside a circle with a radius 3.5 the major axis length
- > If the mean difference of the single object compared to the other objects are above a threshold, mark it as an irregularity



A measure of distance

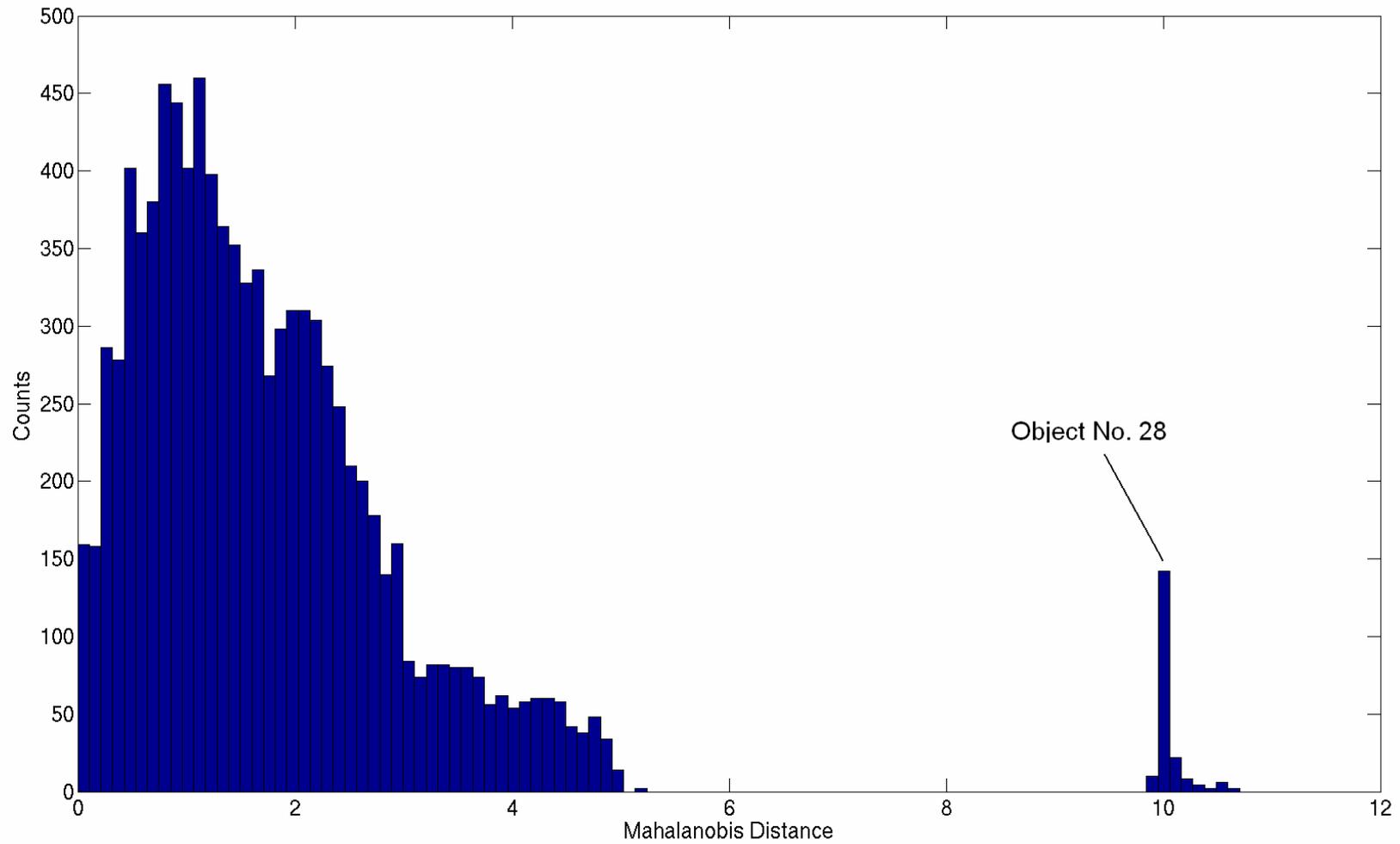
- > x_i and y_i are the i -th entries (e.g. eccentricity, color, area) of the n -tuple describing the two objects

$$d(\vec{x}, \vec{y}) = \sqrt{\sum_{i=1}^N \frac{(x_i - y_i)^2}{\sigma_i^2}},$$

- > The difference is normalized by the variance of this quantity
- > This allows us to compare different properties and their values
 - A difference of 0.3 in eccentricity and a difference of 100 μm^2 of the area of two objects have different ranges
 - When normalizing this, we can compare these distances

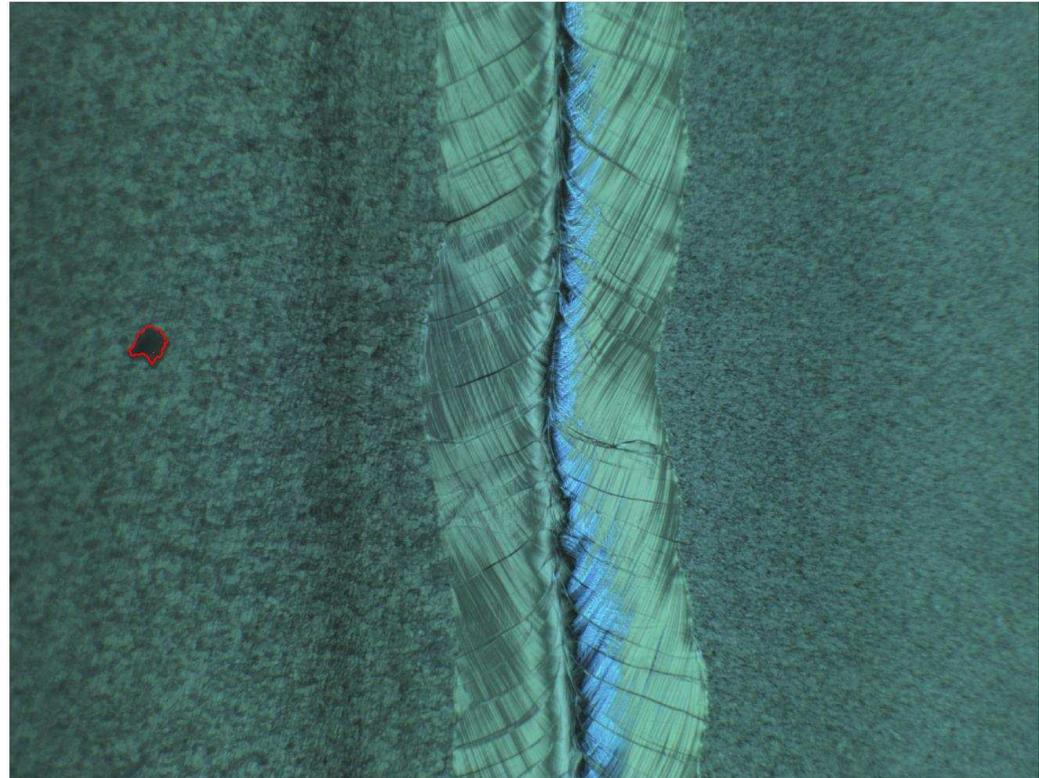


A measure of distance

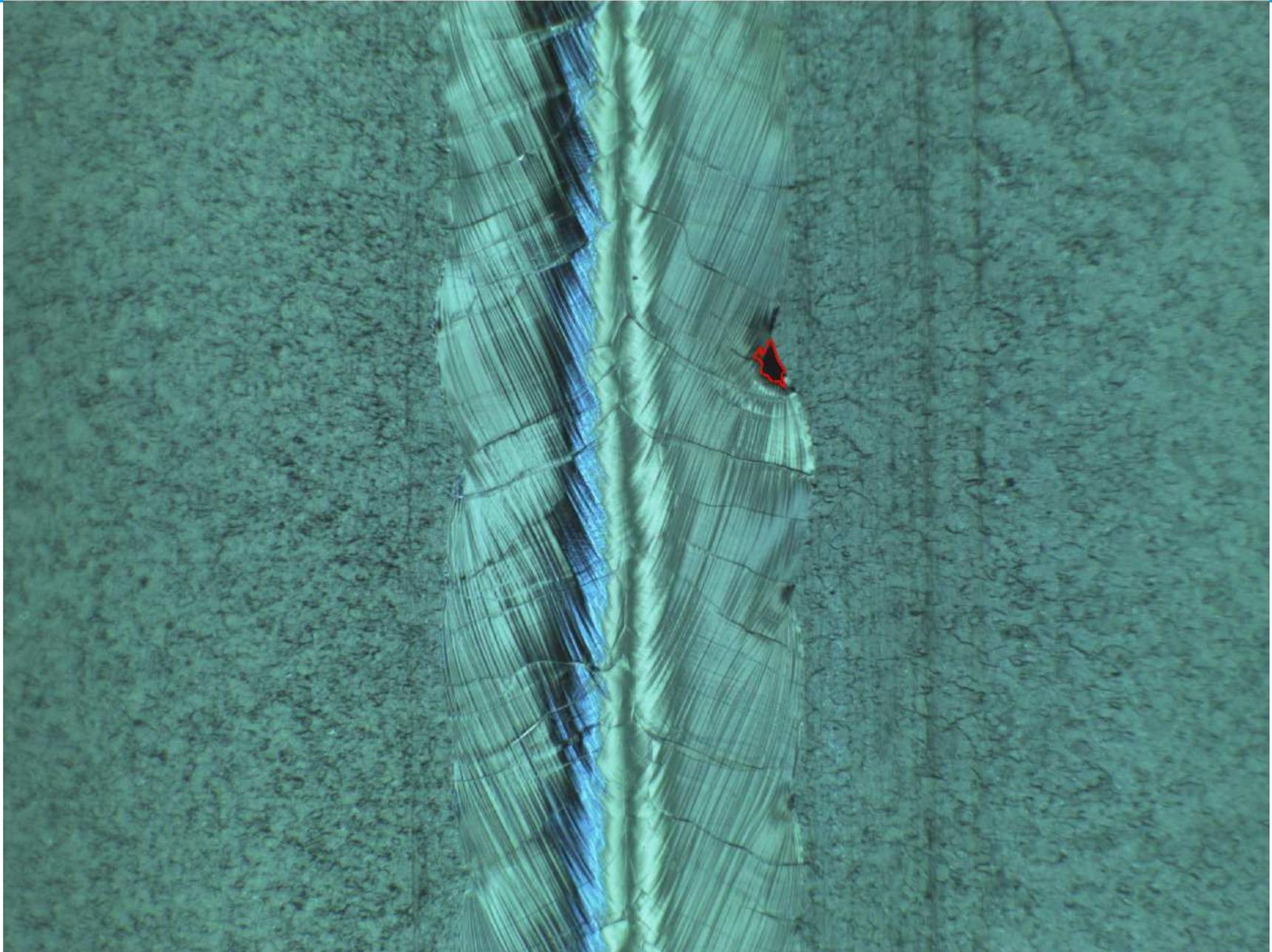


Defect Recognition

- One object was identified as an irregularity
- The boundary of this object is shown in this image
- Fits well with the impurity on the surface



Other defects



Summary

- > OBACHT is being commissioned
- > It will be used for the optical inspection of XFEL and ILC HiGrade cavities
- > An image processing algorithm is being developed to classify the cavity surface properties
- > Defect recognition with obvious defects works (4 different types)



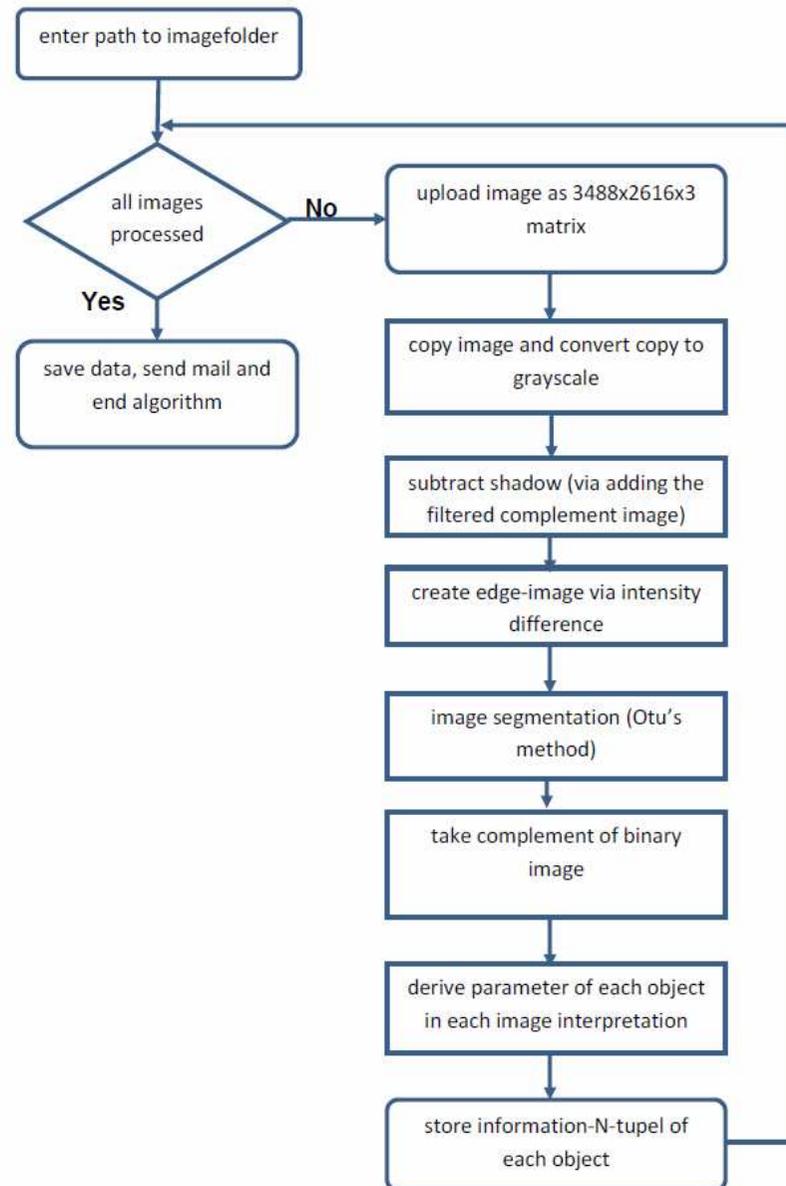
Thank you



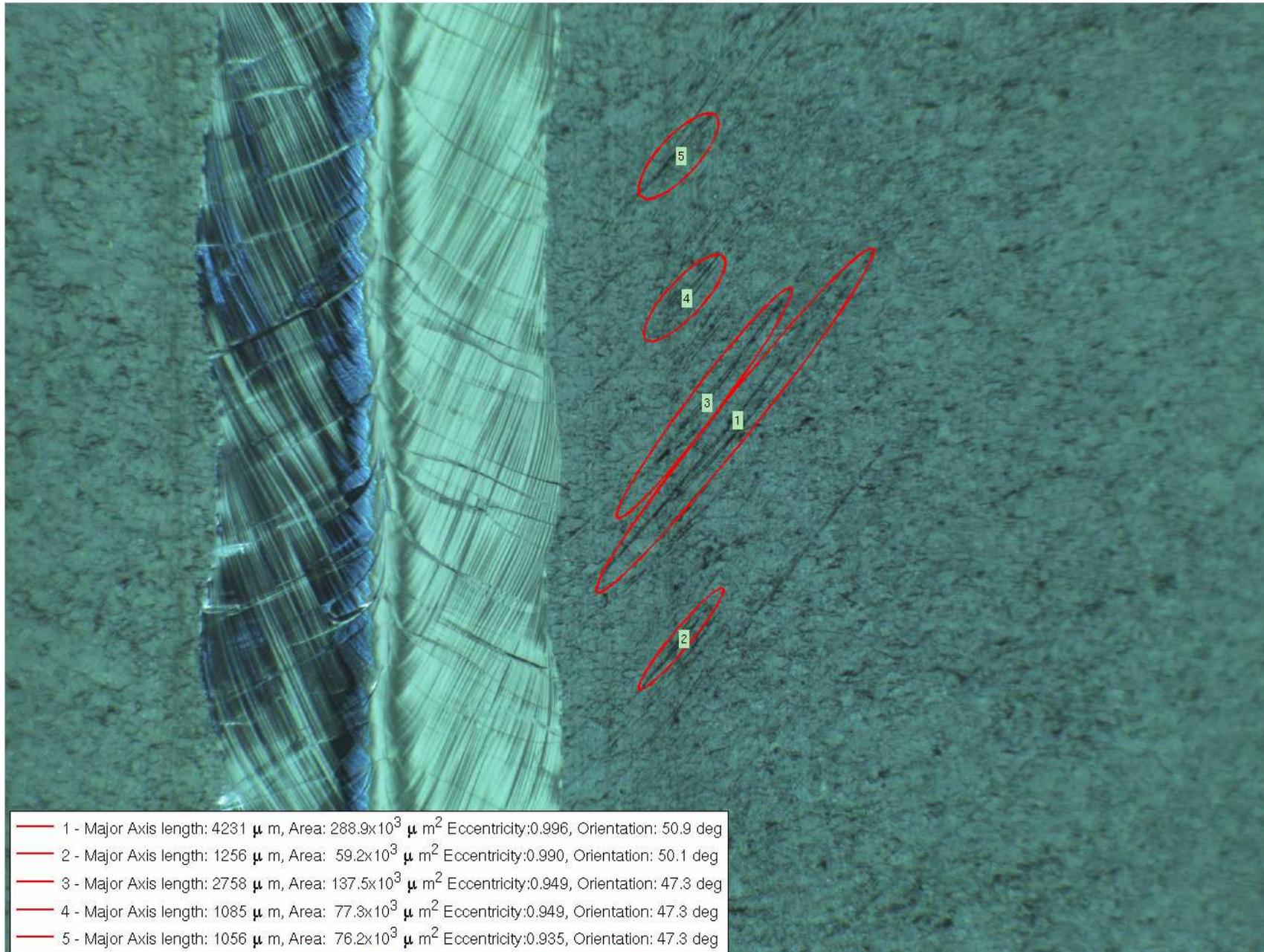
Back Up



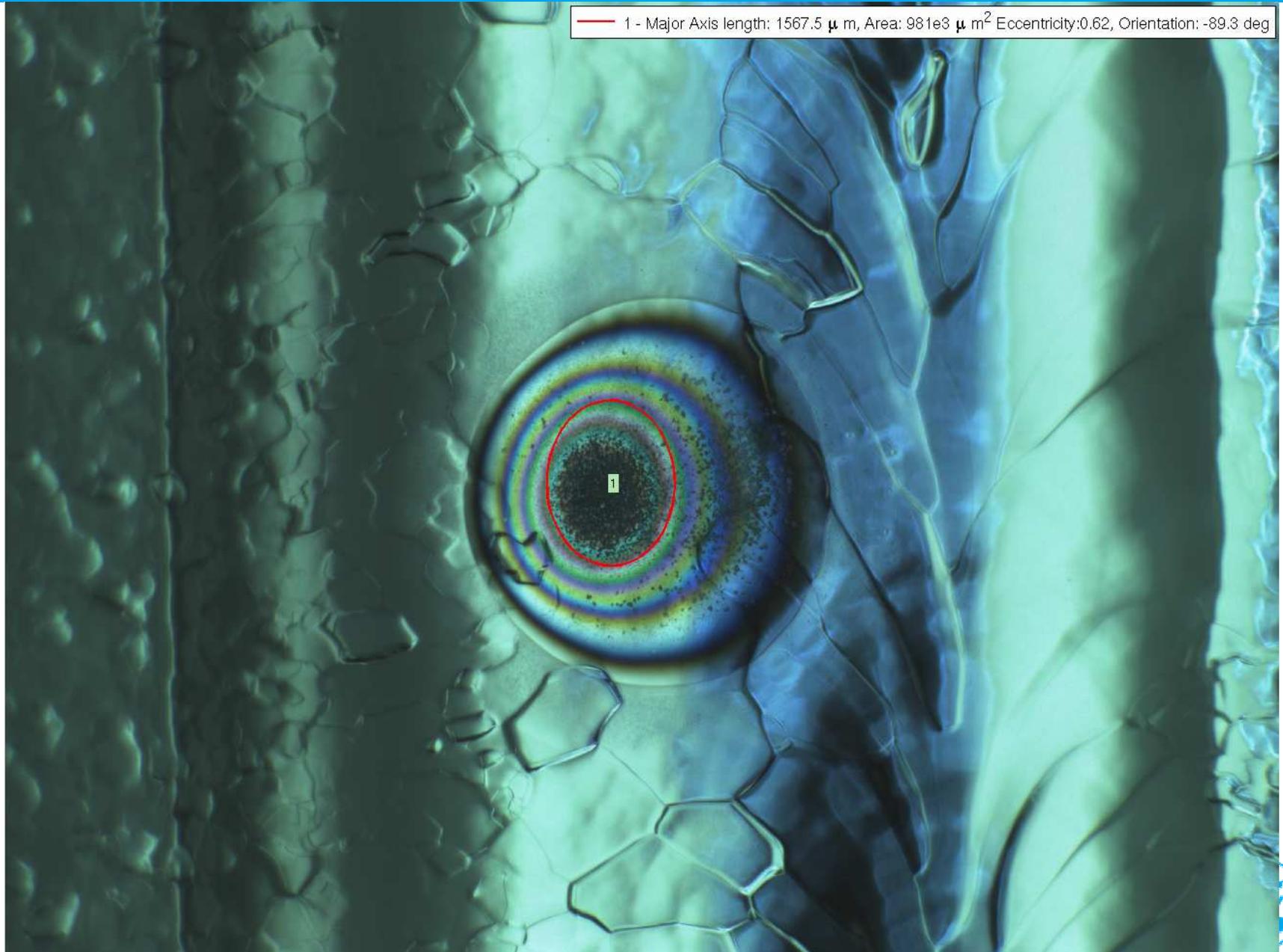
Flowdiagram



Other defects

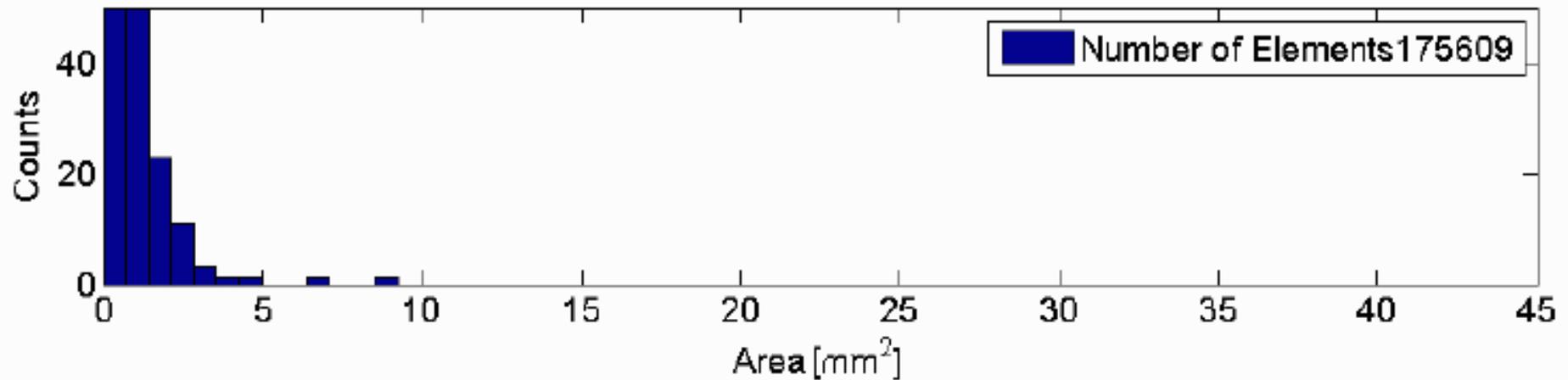


Other defects

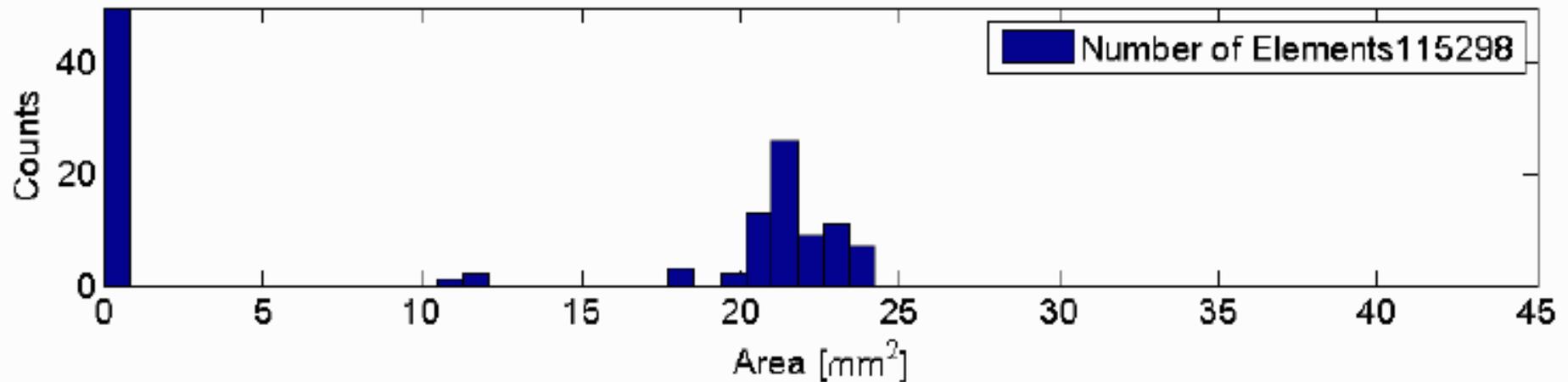


Influence of EP onto the welding seam

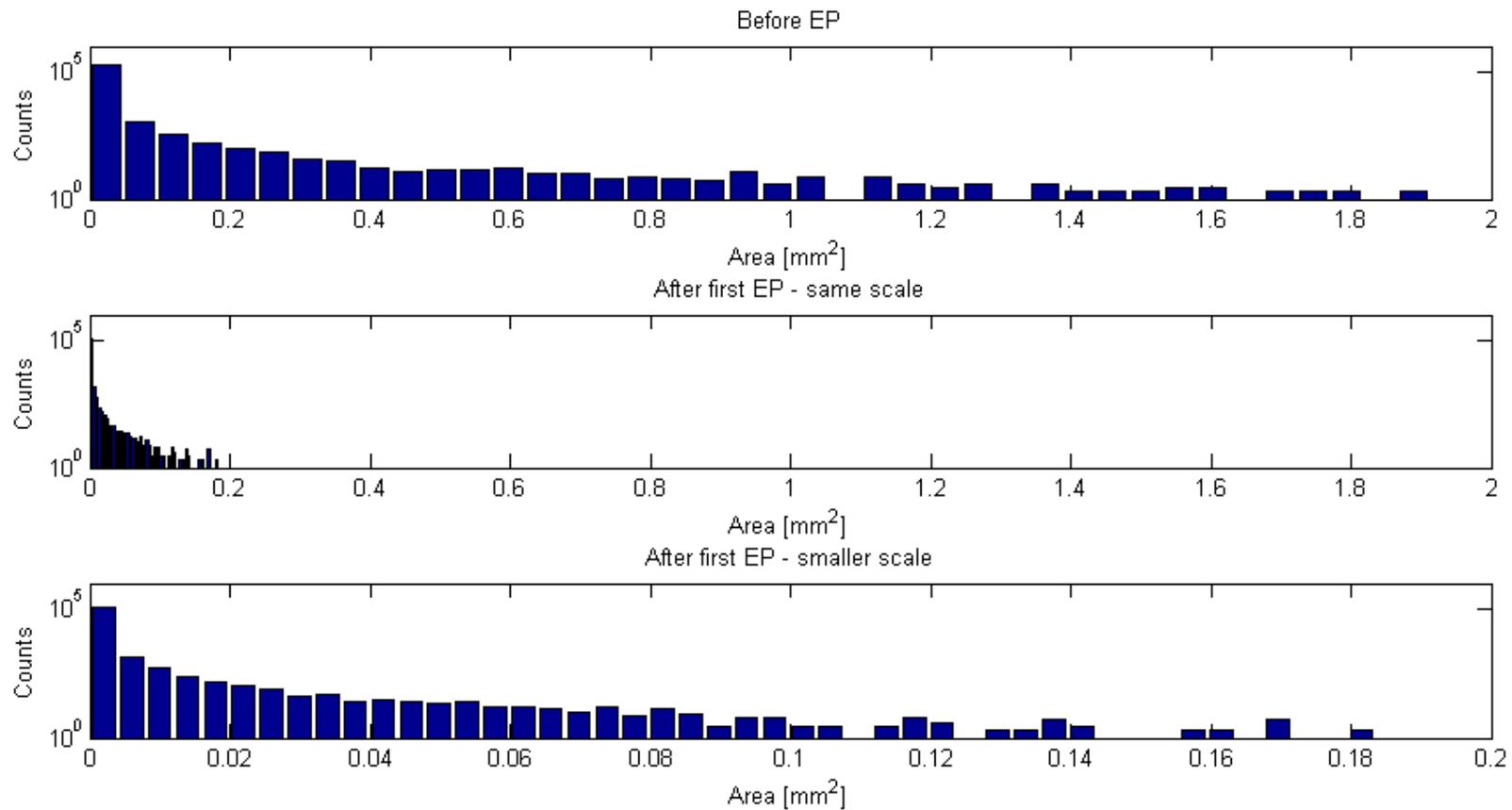
Welding seam at equator 1 - before EP



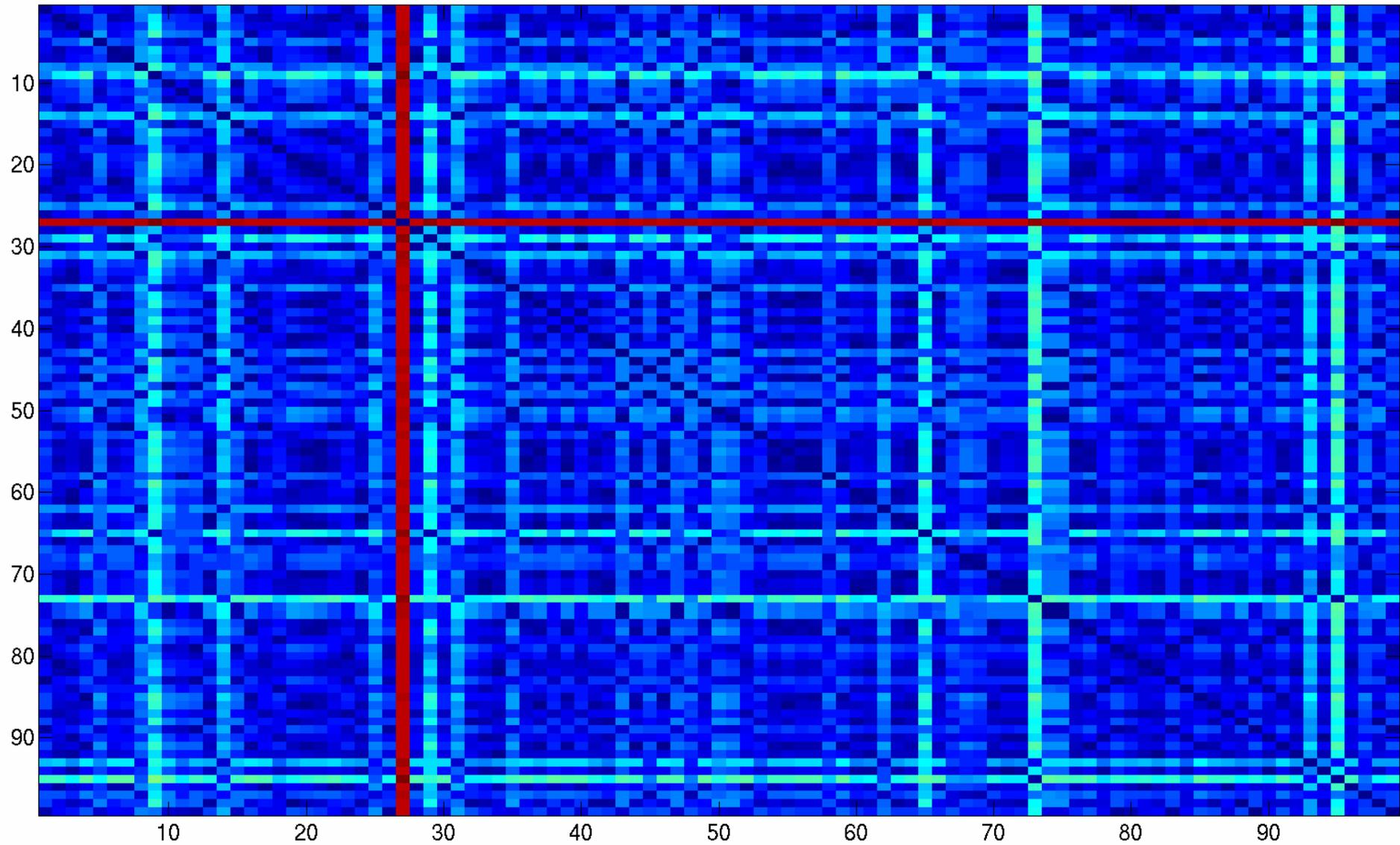
Welding seam at equator 1 - after 1st EP



Influence of EP – objects below 2 mm²

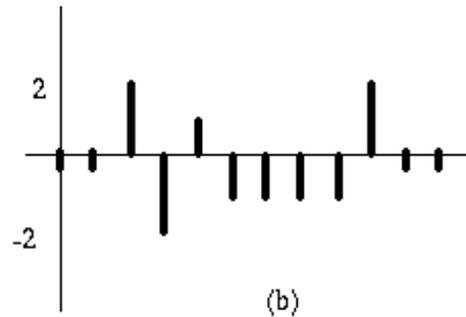
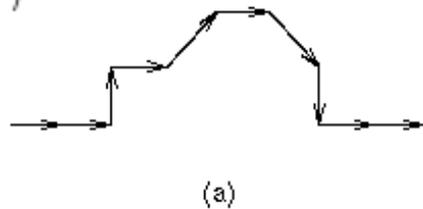


Mahalanobis Distance

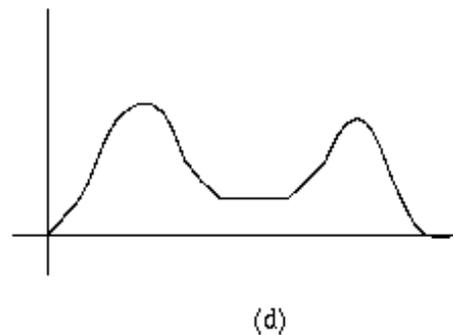
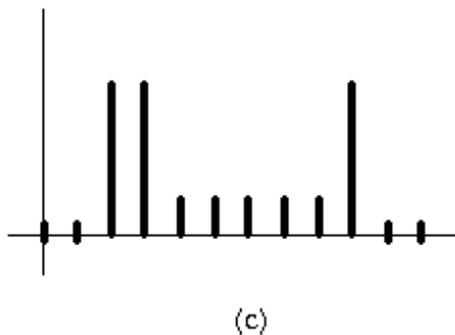


Chaincode – Perimeter – Bending Energy

8-connected



$$\text{Curvature} = \text{mod}(c_{n+1} - c_n, 8)$$

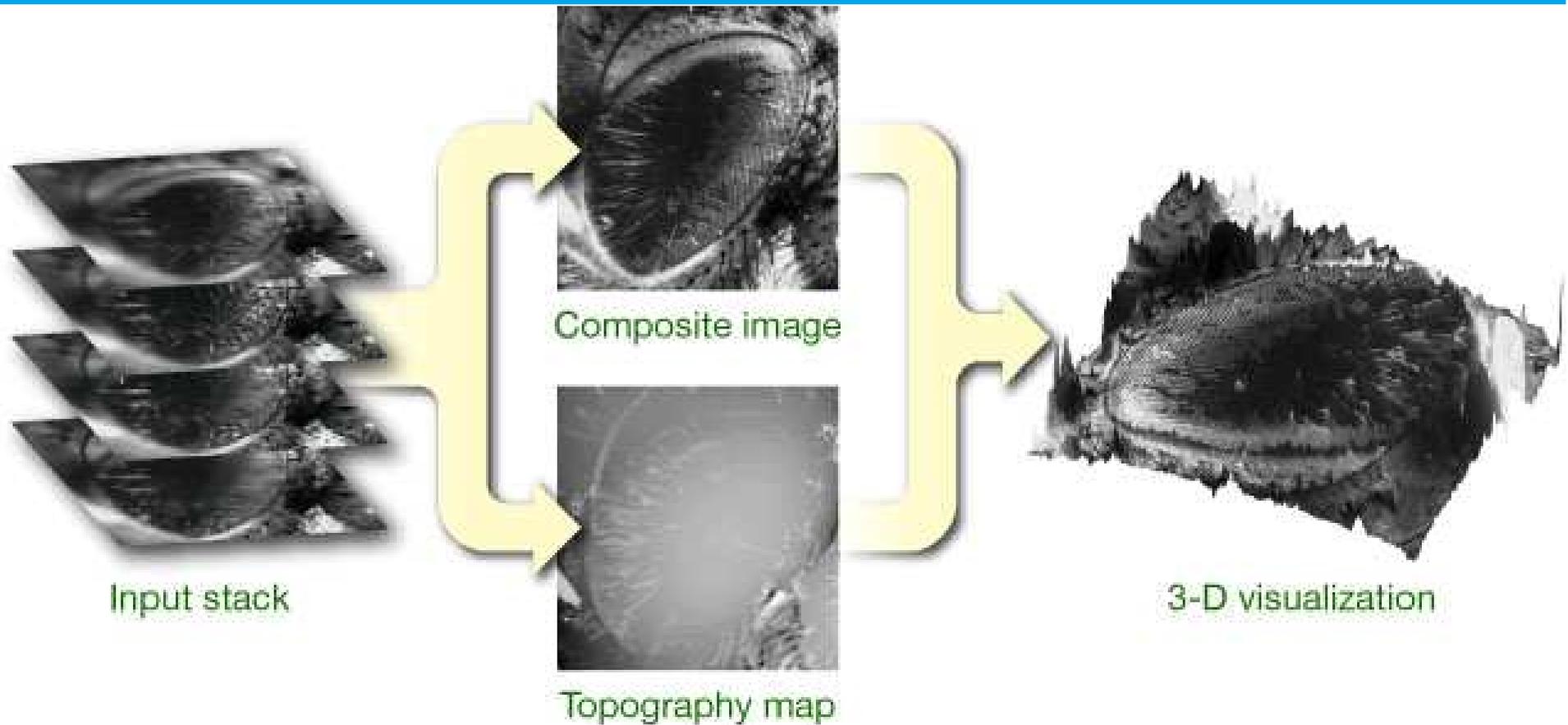


$$\text{BendingEnergy} = \frac{1}{L} \sum \text{Curvature}^2$$

Figure 6.8 Bending energy: (a) Chain code 0, 0, 2, 0, 1, 0, 7, 6, 0, 0, (b) curvature 0, 2, -2, 1, -1, -1, -1, 2, 0, (c) sum of squares gives the bending energy, (d) smoothed version.



2D - 3D

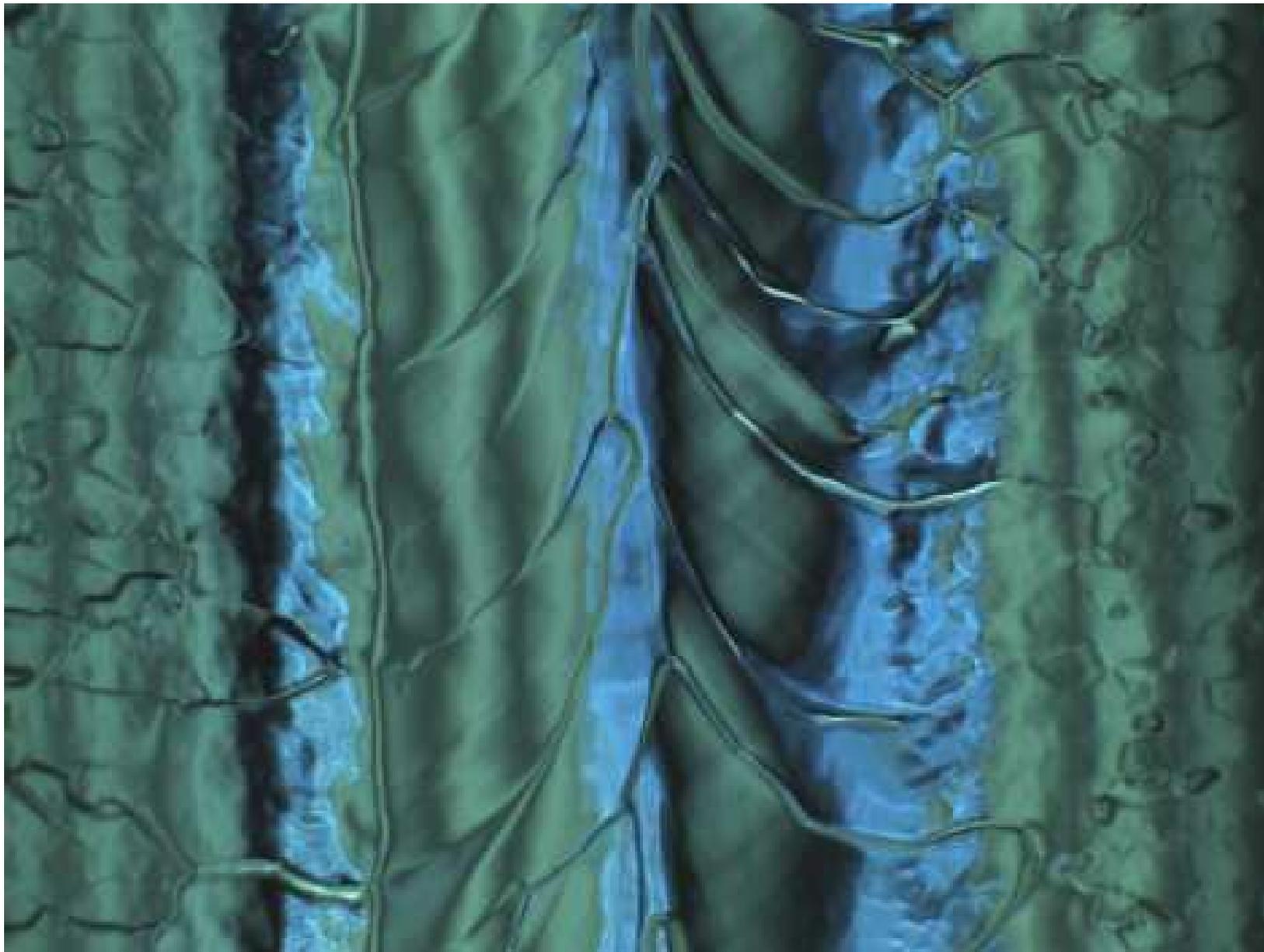


Externes Programm – ‚Complex wavelet-based method‘ (Focus Stacking)

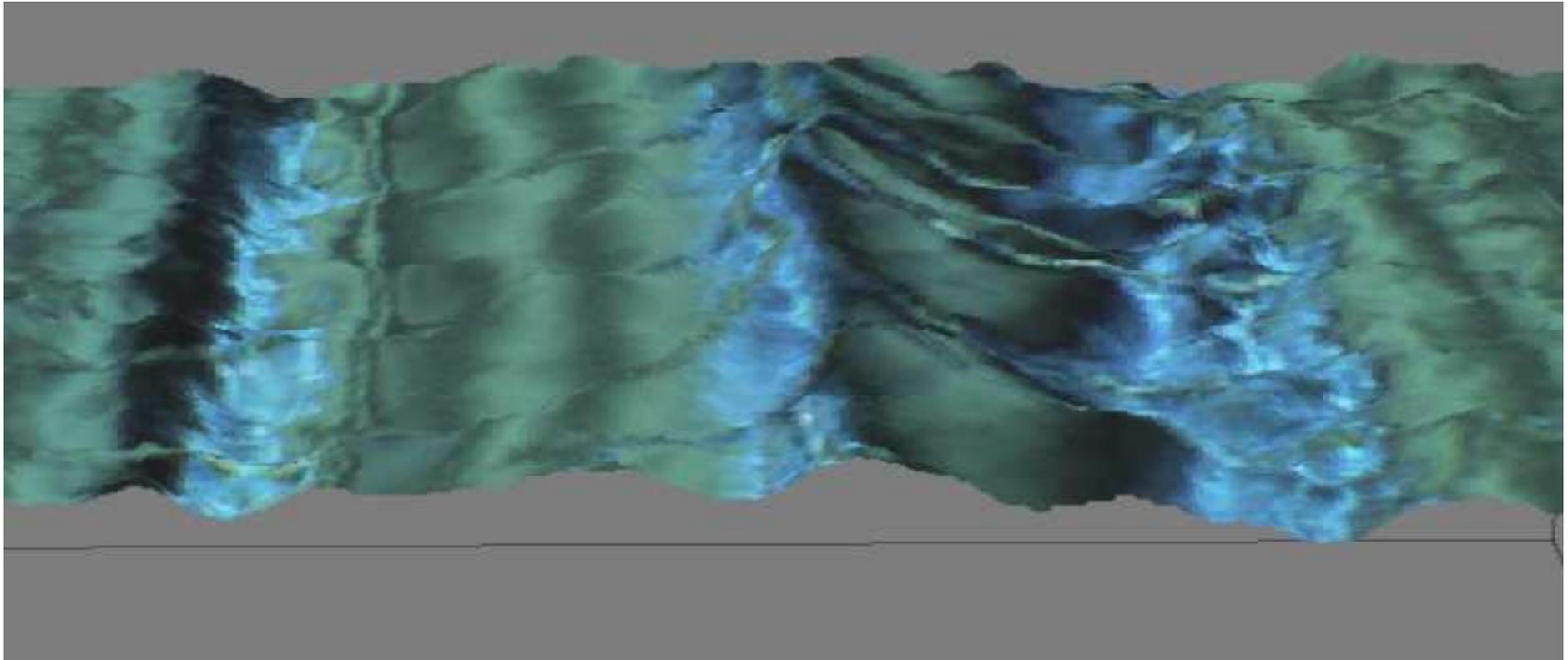
B. Forster, D. Van De Ville, J. Berent, D. Sage, M. Unser,

*"Complex Wavelets for Extended Depth-of-Field: A New Method for the Fusion of Multichannel Microscopy Images
," Microsc. Res. Tech., 65(1-2), pp. 33-42, September 2004.*

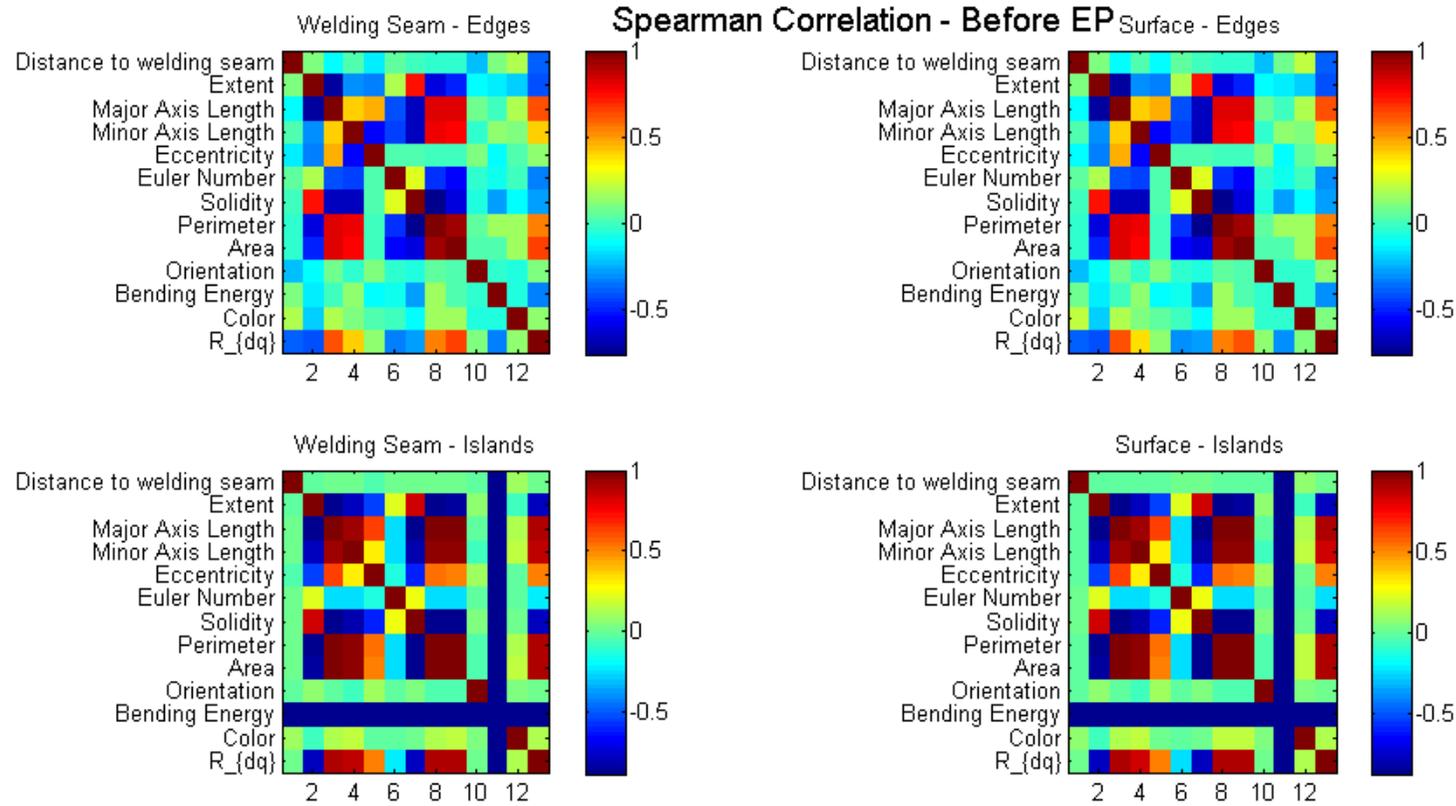
2D - 3D



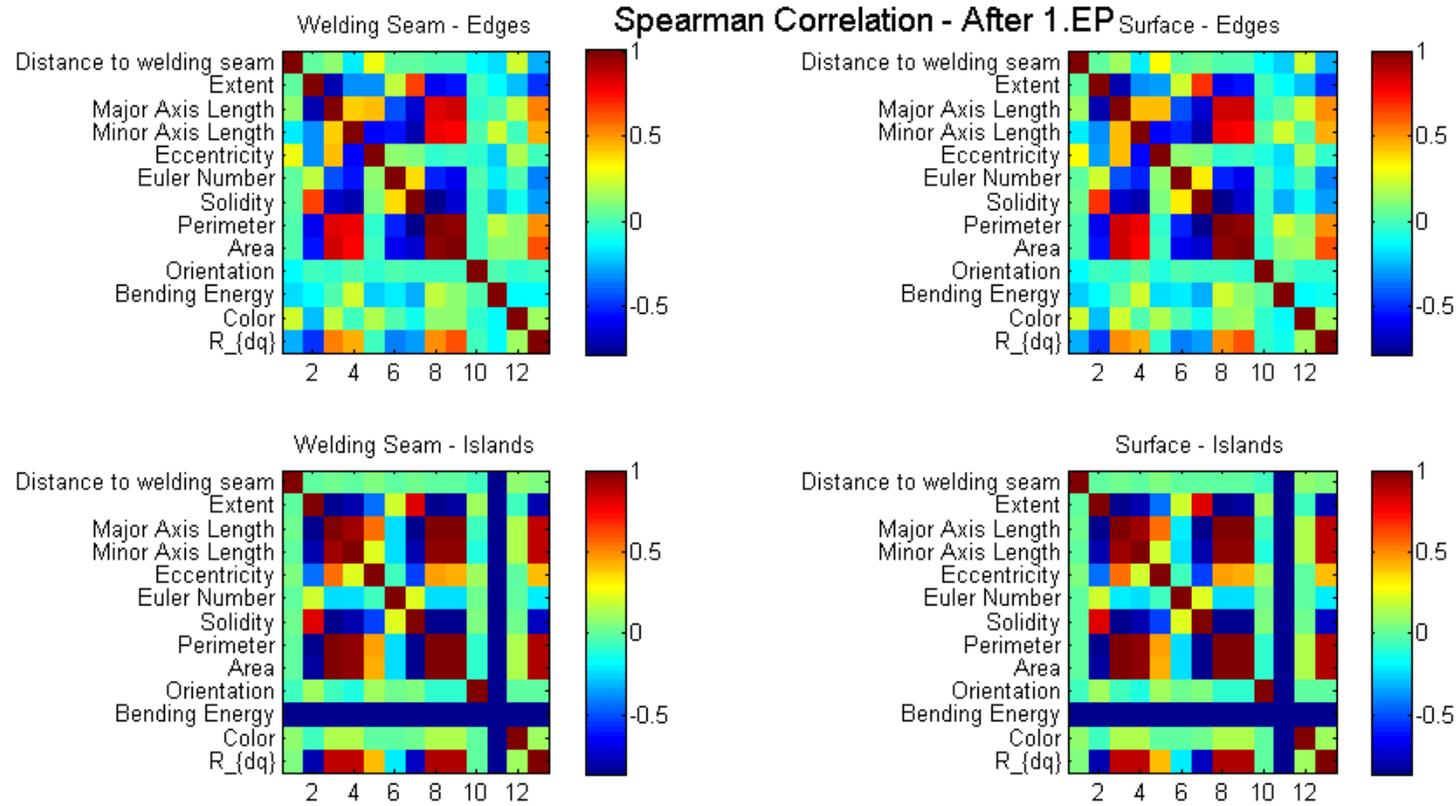
2D - 3D



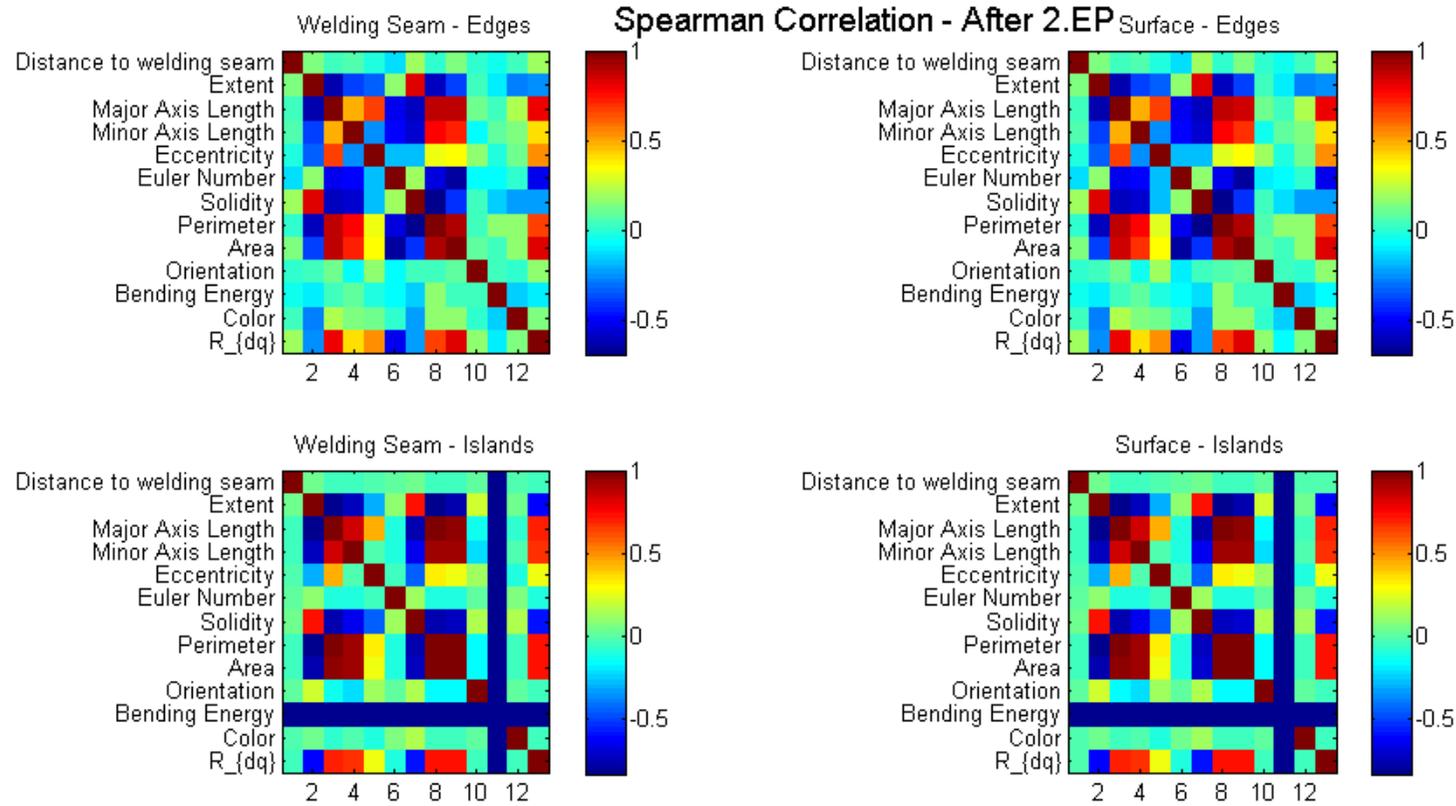
Correlation



Correlation

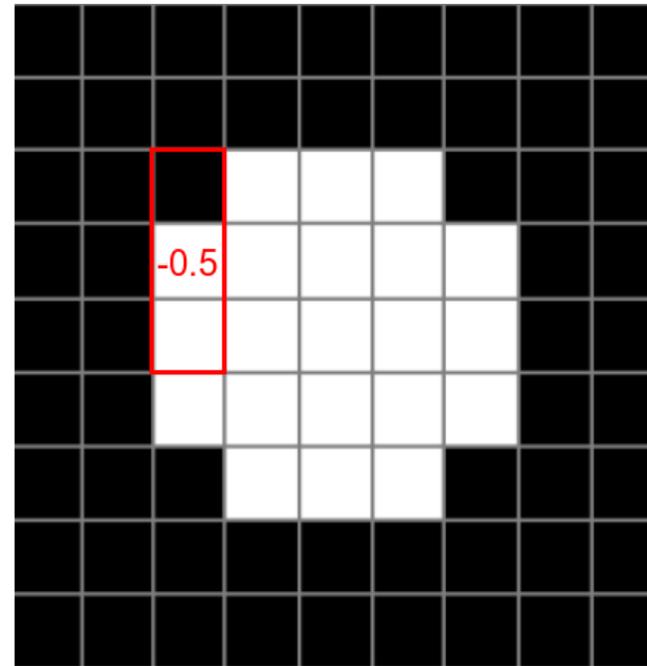
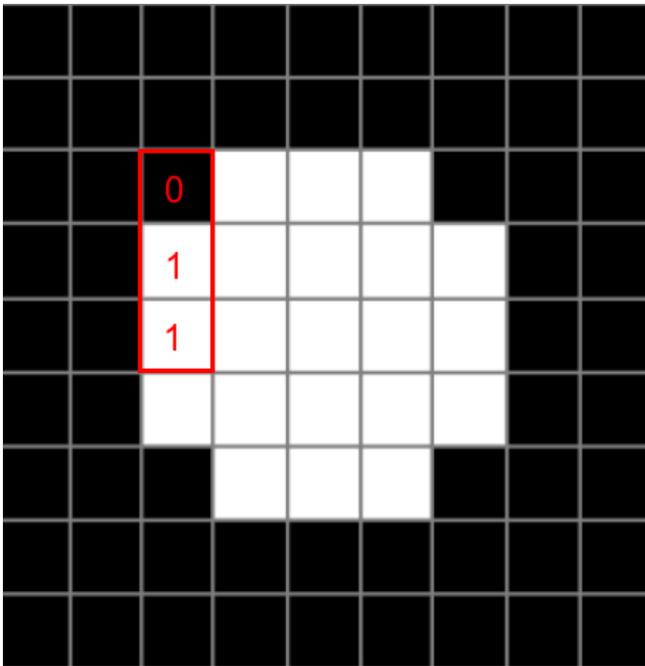


Correlation



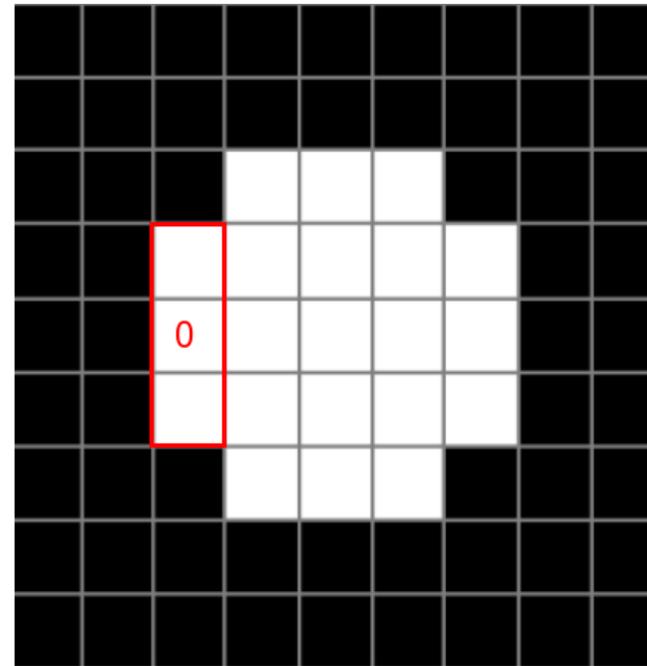
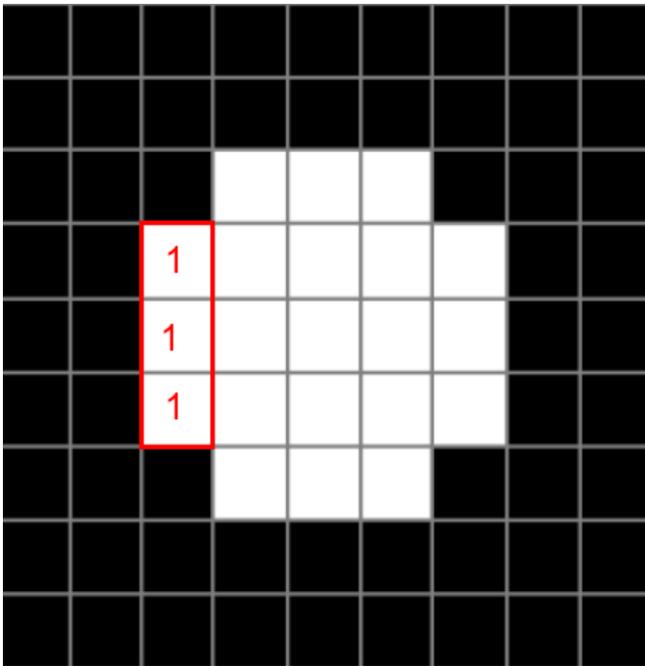
Surface Roughness

$$\frac{\Delta I(x, y)}{\Delta x} = \frac{I(x+1, y) - I(x-1, y)}{(x+1) - (x-1)} = \frac{0 - 1}{2} = -0.5$$



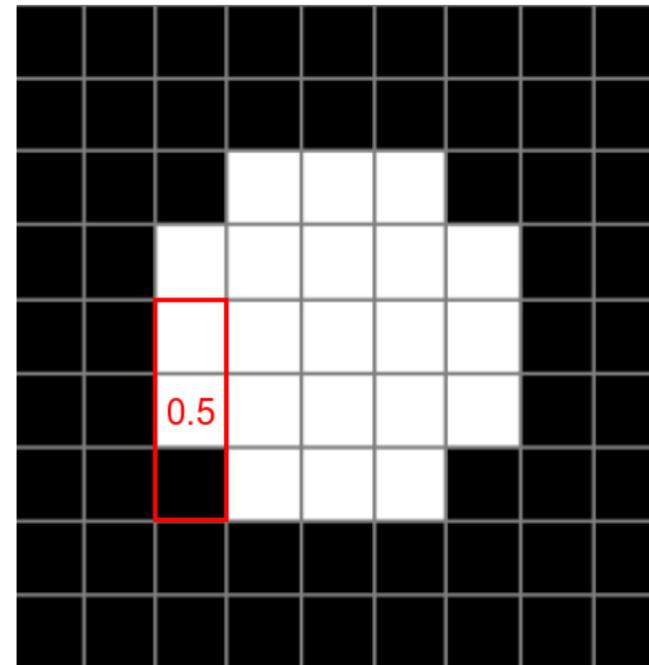
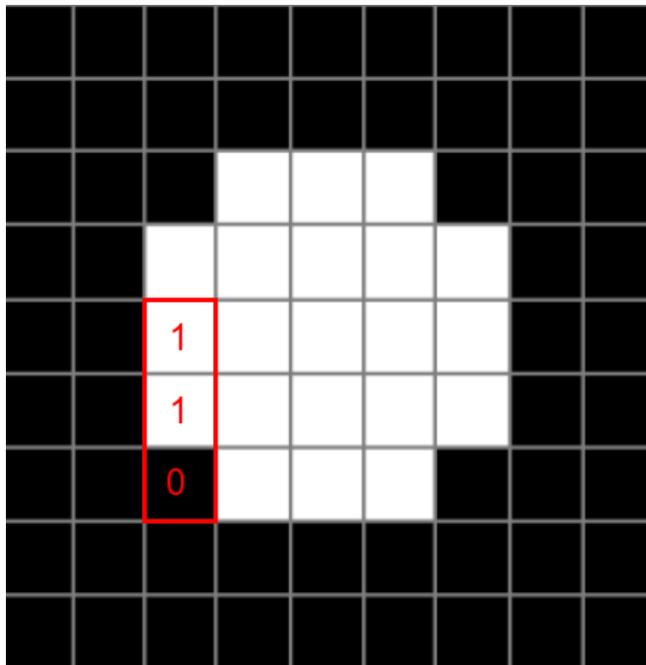
Surface Roughness

$$\frac{\Delta I(x, y)}{\Delta x} = \frac{I(x+1, y) - I(x-1, y)}{(x+1) - (x-1)} = \frac{1-1}{2} = 0$$



Surface Roughness

$$\frac{\Delta I(x, y)}{\Delta x} = \frac{I(x+1, y) - I(x-1, y)}{(x+1) - (x-1)} = \frac{1 - 0}{2} = 0.5$$



Surface Roughness

$$\frac{\Delta I(x, y)}{\Delta x} = \frac{I(x+1, y) - I(x-1, y)}{(x+1) - (x-1)} = \frac{1 - 0}{2} = 0.5$$

